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					Complete if Known			
Substitute for form 1449A/PTO					Application Number	10/551,714		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)					Filing Date	July 20, 2006		
					First Named Inventor	EIN-ELI Yair	EIN-ELI Yair et al	
					Group Art Unit	1793		
					Examiner Name	PARVINI Pegah		
Sheet		1	Of	1	Attorney Docket Number	30579		
		OTHER PRIOR	ART –	NON PATENT	LITERATURE DOCUM	MENTS		
Examiner	Cite	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the						
Initials	No. ¹	item (book, magazine, journal, serial symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.						
	1	Response Dated 04 February 2010 to Official Action of 04 November 2009 From						
			the US Patent and Trademark Office Re.: Application No. 10/551,714.					
	2		Abelev et al. "Enhanced Copper Surface Protection in Aqueous Solutions					
		Containing Short-Chain Alkanoic Acid Potassium Salts", Langmuir, 23: 11281-11288, 2007.						
	3	Abelev et al. "Potassium Sobate Solutions as Copper Chemical Mechanical						
		Planarization (CMP) Based Slurries", Electrochimica Acta, 52: 5150-5158, 2007.						
	4	Abelev et al. "Potassium Sorbate - A New Aqueous Copper Corrosion Inhibitor.						
		Electrochemical and Spectroscopic Studies", Electrochimica Acta, 52: 1975-1982,						
		2007.						
	5	Abelev et al. "Reprint of 'Potassium Sorbate Solutions as Copper Chemical						
		Mechanical Planarization (CMP) Based Slurries", Electrochimica Acta, 53: 1021-						
	-	1029, 2007.						
	6	Ein-Eli et al. "Food Preservatives Serving as Nonselective Metal and Alloy Corrosion Inhibitors", Electrochemical and Solid-State Letters, 9(1): B5-B7, 2006.						
	7	Ein-Eli et al. "Review on Copper Chemical-Mechanical Polishing (CMP) and Post-						
		CMP Cleaning in Ultra Large System Integrated (ULSI) - An Electrochemical						
		Perspective", Electrochimica Acta, 52: 1825-1838, 2007.						

Examiner	Date	
Signature	Considered	

^{*} EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of copy of this form with next communication to applicant.

Applicant's unique citation designation number (optional).

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⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document.

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 $^{^{\}rm 6}$ Applicant is to place a check mark here if English language translation is attached.

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